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Patent and Trademark OfficeAttorney's Docket No.  
10559-887001Application No.  
10/649,354**Information Disclosure Statement  
by Applicant**

(Use several sheets if necessary)

Applicant  
Florence Eschbach et al.Filing Date  
August 26, 2003Group Art Unit  
1773**U.S. Patent Documents**

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
VC	AA	2003/0187168	10/2003	Sunaga et al.			
	AB	2005/0202252	09/2005	Tregub et al.			
	AC	2005/0203254	09/2005	Tregub et al.			
	AD	4,737,387	04/1988	Yen			
	AE	5,880,204	03/1999	McCarthy et al.			
	AF	6,111,062	08/2000	Shirota et al.			
	AG	6,548,129	04/2003	Matsukura et al.			
VC	AH	6,652,958	11/2003	Tobita			

**Foreign Patent Documents or Published Foreign Patent Applications**

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
VC	AI	0 252 673	01/1988	Europe				
VC	AJ	0 416 528	03/1991	Europe				

**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Initial	Desig. ID	Document
VC	AK	Karis, et al., "Characterization of a solid fluorocarbon film on magnetic recording media", <i>J. Vac. Sci. Technol. A</i> , 15(4):2382-2387, (1997).
	AL	Karis, et al., "Tribology of a Solid Fluorocarbon Film on Magnetic Recording Media", <i>IEEE Transactions on Magnetics</i> , 34(4):1747-1749, (1998).
	AM	LaPedus, M., "Nikon evaluating 157-nm lithography options", <i>EE Times UK</i> , <a href="http://www.eetuk.com/tech/news/dev/OEG20030523S0061">http://www.eetuk.com/tech/news/dev/OEG20030523S0061</a> , May 24, 2003.
	AN	Resnick & Buck, "Teflon® AF Amorphous Fluoropolymers", <i>Modern Fluoropolymers</i> , Edited by J. Schews, John Wiley & Sons, Inc., pp. 397-419, (1997).
	AO	Seki, et al., "Electronic Structure of Poly(tetrafluoroethylene) Studied by UPS, VUV Absorption, and Band Calculations", <i>Physica Scripta</i> , 41(1):167-171, (1990).
	AP	Singer, P., "Atomic Layer Deposition Targets Thin Films", <i>Semiconductor International</i> , 22(10):40, (1999).
	AQ	Sugiyama, "Perfluoropolymers Obtained by Cyclopolymerization and Their Applications", <i>Modern Fluoropolymers</i> , Edited by J. Schews, John Wiley & Sons, Inc., pp. 541-555, (1997).
	AR	Theirich, et al., "A novel technique for high rate plasma polymerization with radio frequency plasmas", <i>Surface and Coatings Technology</i> , 86-87, pp. 628-633, (1996).
VC	AS	Walton, K.R., "The Lubrication of Gold Surfaces by Plasma-Deposited Thin Films of Fluorocarbon Polymer," <i>IEEE Transactions on Components, Hybrids, and Manufacturing Technology</i> , CHMT-3(2):297-304, (1980).

Examiner Signature

/Vivian Chen/

Date Considered

09/29/2006

EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.